

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Gabric, *et al.* Docket No: 2006 VJ 33543 US
Filed: Herewith Art Unit: TBD
Serial No.: Not Assigned Examiner: TBD
For: Plasma Excited Chemical Vapor Deposition Method, Silicon/Oxygen/Nitrogen-
Containing-Material and Layered Assembly

Mail Stop PCT
Commissioner for Patents
P. O. Box 1450
Alexandria, VA 22313-1450

PRELIMINARY AMENDMENT

Dear Sir:

Applicant respectfully requests entry of this preliminary amendment prior to Examiner's
examination of the application.